

FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. 58620.00010	SERIAL NO. <i>161830133</i> New Application
LIST OF REFERENCES CITED BY APPLICANT <i>(Use several sheets if necessary)</i>		APPLICANT SBERVEGLIERI et al	
		FILING DATE April 23, 2004	GROUP <i>2856</i> Not yet assigned

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NO.	DATE	NAME	CLASS	SUB-CLASS	FILING DATE
AA						

OTHER REFERENCES (*Including Author, Title, Date, Pertinent Pages, Etc.*)

/JF/	AL	Sberveglieri et al, "Highly Sensitive and Selective NO <sub>x</sub> and NO <sub>2</sub> Sensor Based on Cd-doped SnO <sub>2</sub> Thin Films," Sensors and Actuators B, 4, 1991, pages 457-461.
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		Ferroni et al, "Gas-Sensing Applications of W-Ti-O-based nanosized thin films prepared by r.f. reactive sputtering", Sensors and Actuators B, 44, 1997, pages 499-502.
		Faglia et al, "Electrical and structural properties of RGTO-In <sub>2</sub> O <sub>3</sub> sensors for ozone", Sensors and Actuators B 57, 1997, pages 188-191
		Comini et al, "Carbon monoxide response of molybdenum oxide thin films deposited by different techniques", Sensors and Actuators B 68, 2000, pages 168-174.
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EXAMINER	/John Fitzgerald/	DATE CONSIDERED 08/10/2007

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. 58620.00010	SERIAL NO. 10/830,133
LIST OF REFERENCES CITED BY APPLICANT <i>(Use several sheets if necessary)</i>		APPLICANT Giorgio SBERVEGLIERI et al.	
		FILING DATE April 23, 2004	GROUP 1753-2856

*O I P E S C T Y*  
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## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NO.	DATE	NAME	CLASS	SUB-CLASS	FILING DATE
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/JF/	AB	4,389,373	June 21, 1983	Linder et al.			
/JF/	AC	4,457,161	July 3, 1984	Iwanaga et al.			
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	AE						
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		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION
							YES NO PART.
	AG						
	AH						
	AI						
	AJ						
	AK						

OTHER REFERENCES (*Including Author, Title, Date, Pertinent Pages, Etc.*)

	AL	
	AM	
	AN	

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